

Claims

1. A substrate processing system, comprising:
 - a substrate support disposed in a processing chamber, the substrate support having a substrate support surface and a plurality of lift pins arranged to support a substrate above the substrate support surface when lifted with respect to the substrate support; and
 - a substrate transfer robot including a support surface and a plurality of contact elements arranged to support the substrate when disposed on the substrate transfer robot,
 - wherein all of the substrate support surface, the plurality of contact elements, and the plurality of lift pins are formed of a material having a hardness equal to a silicon hardness, having low adhesion, having a coefficient of static friction large enough to prevent sliding, having a surface roughness equal to 10 Ra, and that is electrically conductive, wherein the material comprises aluminum oxide, silicon nitride, and stainless steel.